Configurations:

Reticle Blind		Setting value	44583
XM Outside		400 ~ 800 um	650
XP Inside		400 ~ 800 um	650
YM Outside		400 ~ 800 um	610
YP Inside		400 ~ 800 um	620
Lens performance Data			
Illumination Check		Setting value	44583
ID1	Uniformity	≤ 0.8 %	0.0056
	Power	> 3000 mw/cm2	3177
ID13	Uniformity	≤ 0.8 %	0.00346
	Power	> 3000 mw/cm2	2533
ID15	Uniformity	≤ 0.8 %	0.00433
	Power	> 3000 mw/cm2	2544
ID17	Uniformity	≤ 0.8 %	0.00592
	Power	> 3000 mw/cm2	2568
ID21	Uniformity	≤ 0.8 %	0.00508
	Power	> 3000 mw/cm2	3129
Wafer Stage Mirror Bow		Setting value	44583
Upper	Sub value X	≤ 8 nm	1.695
	Sub value Y	≤ 8 nm	1.053
Lower	Sub value X	≤ 8 nm	1.133
	Sub value Y	≤ 8 nm	0.919
Twist	Sub value X	≤ 8 nm	5.337
	sub value Y	≤ 8 nm	4.39
		Setting value	44583
Projection Lens Image Plane	Angle X	0 ± 1 urad	-0.051
	Angle Y	0 ± 3 urad	0.511
Field Inclination TFD	max - min	≤ 0.080 um	0.0675
	All reading have?	Yes / No	YES
Flare check(Please inform EE when E0<=240mj)	E0	>=240 mj	360
Best Focus		0 ± 0.015 um	0.004
Wafer Loader Repeatability (Front)		Setting value	44583
Y 3Sigma		≤ 15 um	3.955
Rot 3Sigma		≤ 200 um	112.742
X 3Sigma		≤ 15 um	7.137
Rot mean		0 ± 200 um	141.461
Y mean		0 ± 10 um	1.758
X mean		0 ± 10 um	1.906
FIA Overlay Matching		Setting value	44583

Residual X 3Sigma		< 20nm	15.6
Residual Y 3Sigma		< 20nm	12.8
Plus/Minus Difference X		< 10nm	1.4
Plus/Minus Difference Y		< 10nm	4.5